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Patent No. : 6,949,469 B1
Inventor(s) : Yu Cheng, et al.
Issued : September 27, 2005
For **METHODS AND APPARATUS FOR
THE OPTIMIZATION OF PHOTO RESIST
ETCHING IN A PLASMA PROCESSING
SYSTEM**
Doc. No. **LMRX-P029/P1180**

To Whom It May Concern:

The Certificate of Correction issued on May 2, 2006, issued in error, in that error(s) was made in identifying the patent number and/or keying text/corrections, i.e.:

The issue date in the heading of cofc has been incorrectly entered on SB44 form submitted by attorney. In future instances, in the heading of the cofc the patent issue date should be displayed not the filing date or the date of filing of the request for cofc.

Therefore, a certificate of correction will be issued to correct (supersede) the Certificate of Correction containing error(s), made during preparation of the Certificate of Correction, as noted above.

No further response is required, from applicants (attorney). However, errors discovered by attorney, other than as noted and described above, should be noted on *a copy* of the Certificate of Correction that was issued in error, accompanied by a signed transmittal letter and submitted directed to this Branch.

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cbn